

Practitioner's Docket No.: L&L-I0242

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Laurence A. GreenbergJanuary 9, 2006
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/694,593 Confirmation No.: 3503
Applicant : Olaf Storbeck, et al.
Filed : October 27, 2003
Title : Method for Minimizing the Vapor
Deposition of Tungsten Oxide During the
Selective Side Wall Oxidation of
Tungsten-Silicon Gates
Art Unit : 2823
Examiner : Fernando L. Toledo
Customer No. : 24131

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R E S P O N S E

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S i r :

Responsive to the Office action dated October 14, 2005,
kindly consider the following remarks:

Remarks/Arguments begin on page 2 of this paper.